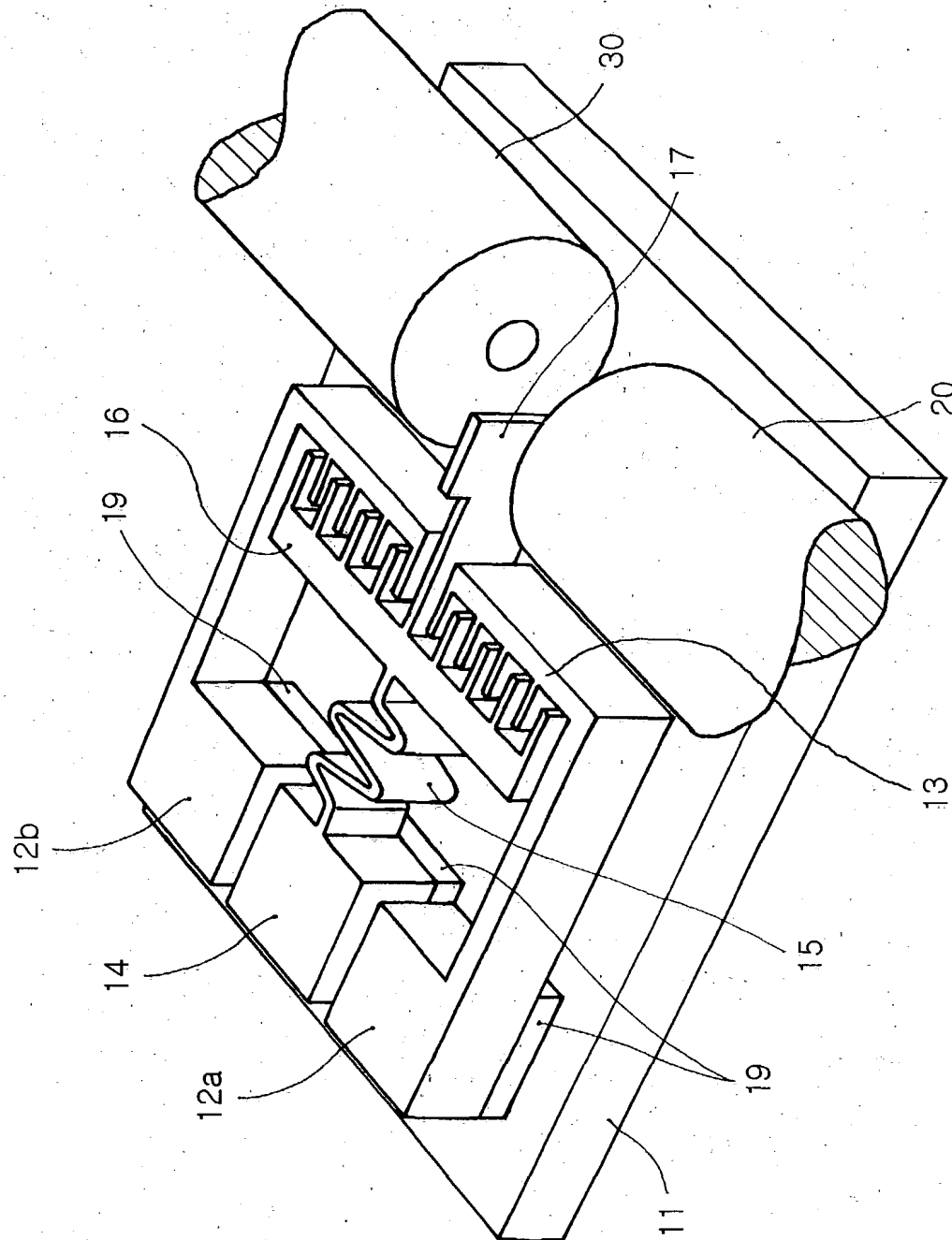


MICROELECTROMECHANICAL SYSTEMS (MEMS) VARIABLE OPTICAL ATTENUATOR

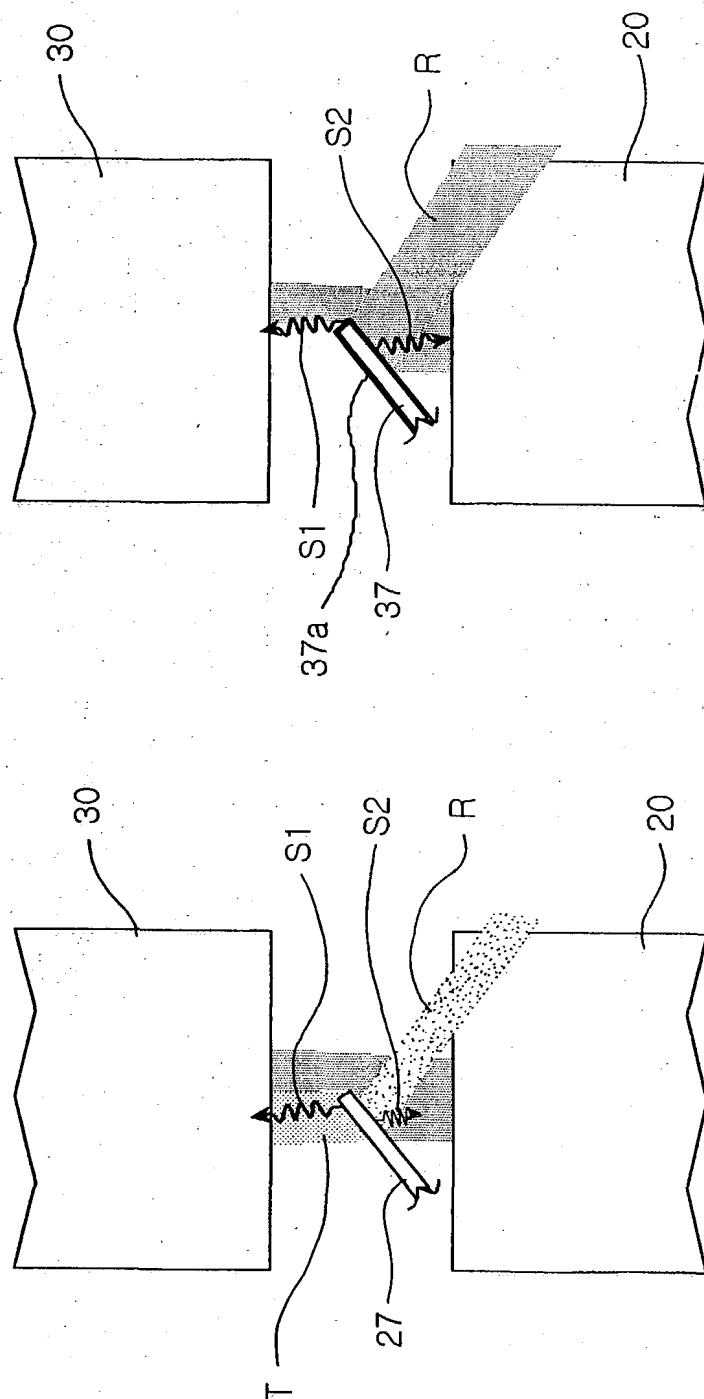
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PRIOR ART



PRIOR ART

FIG. 2b

PRIOR ART

FIG. 2a

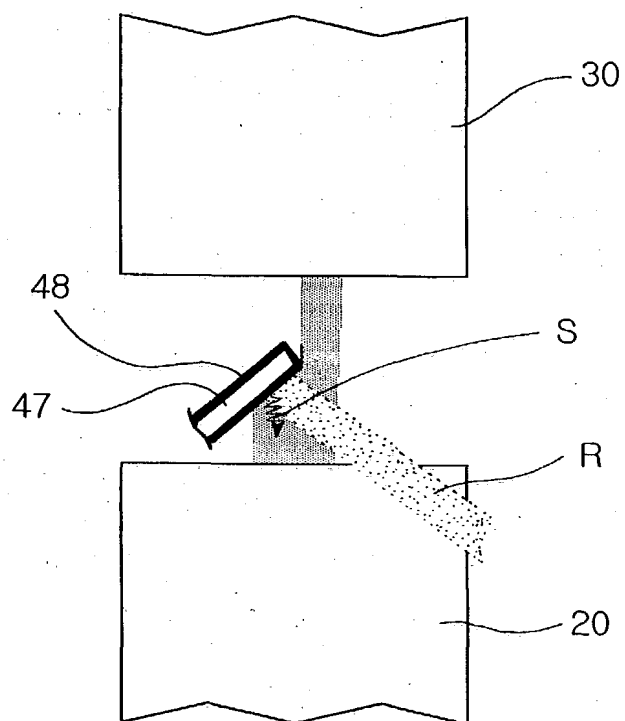


FIG. 3

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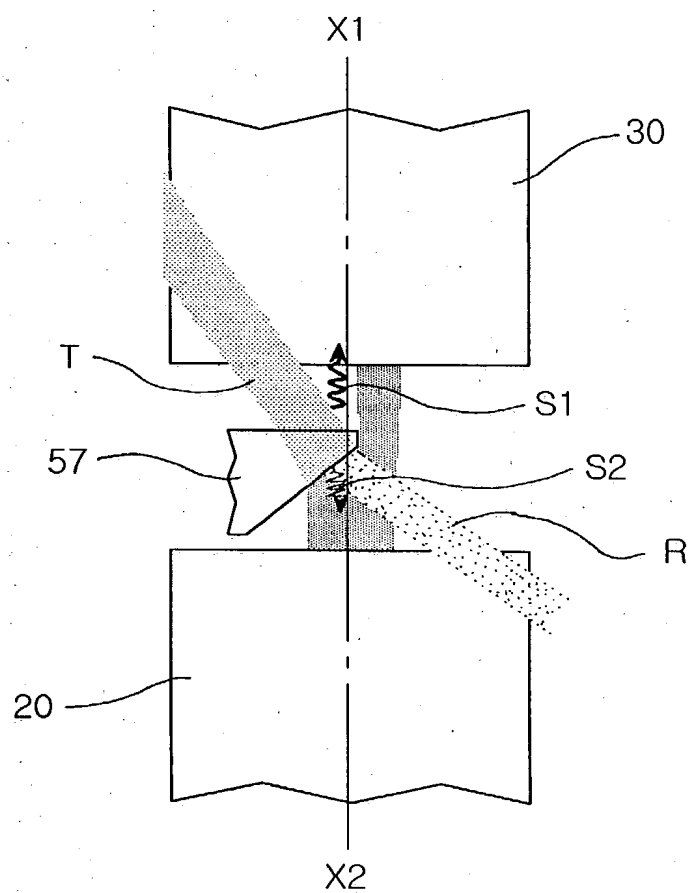


FIG. 4

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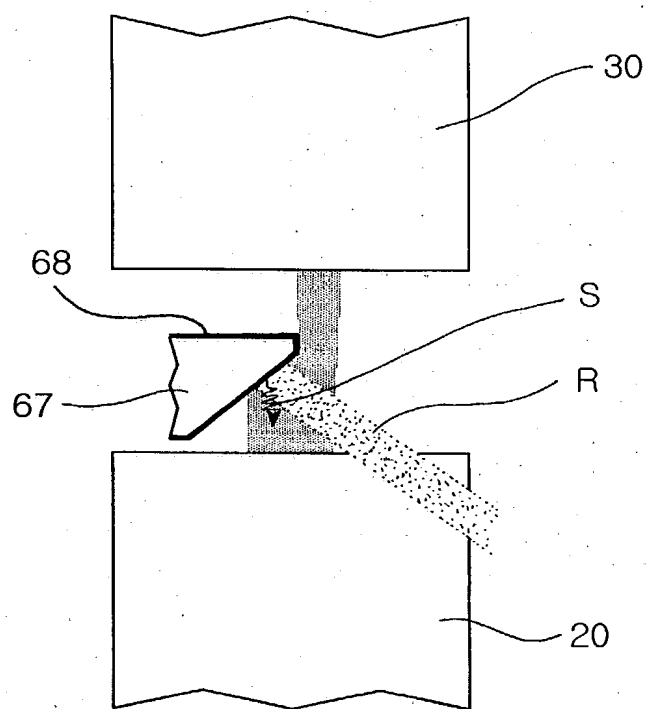


FIG. 5

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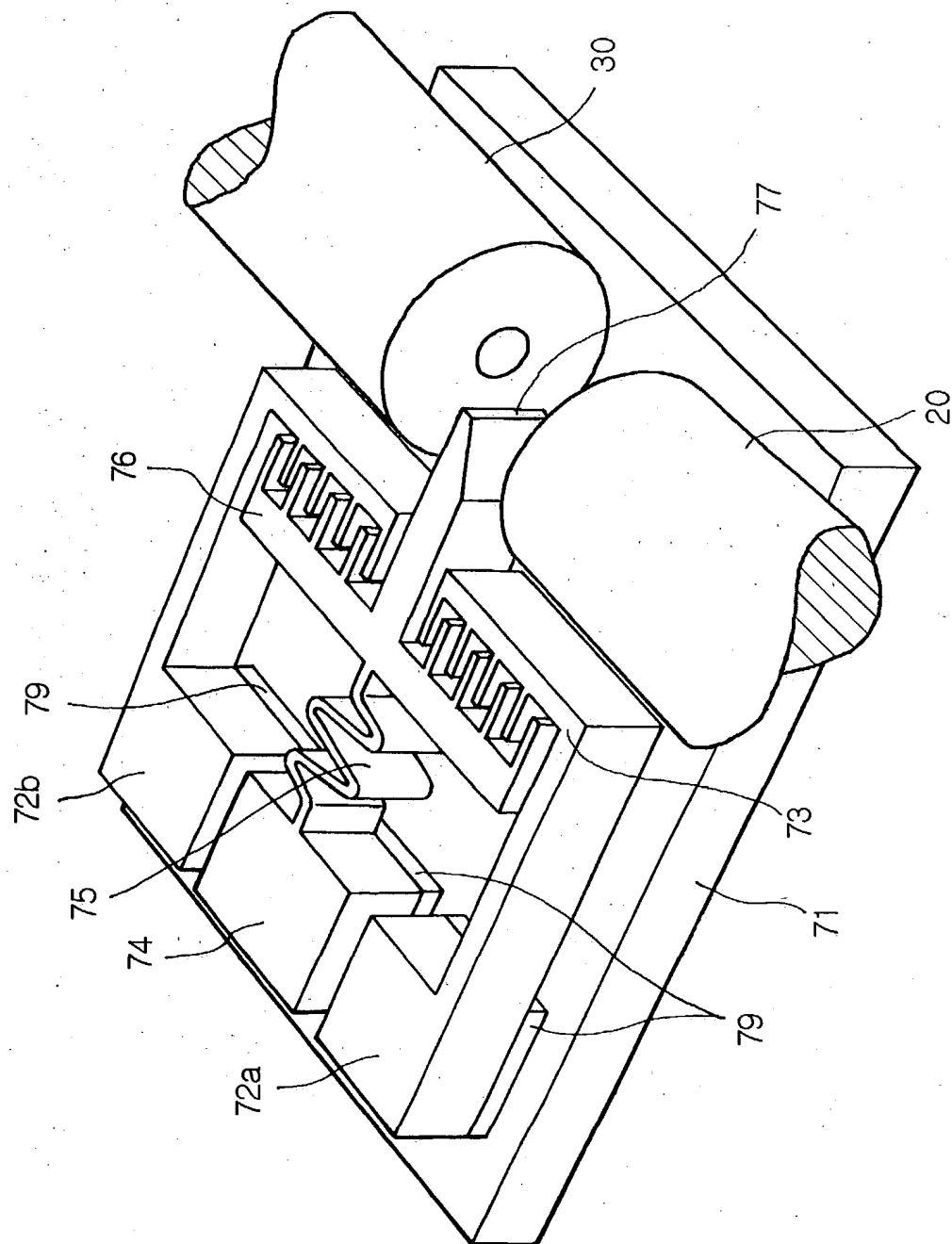


FIG. 6

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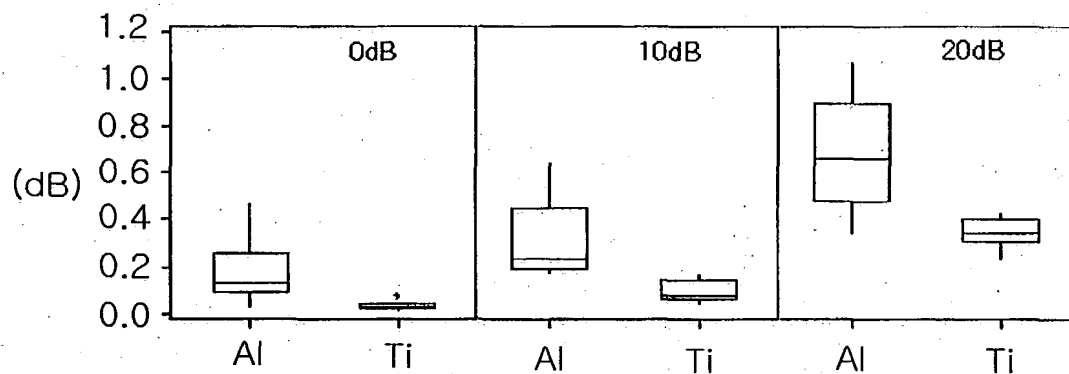


FIG. 7a

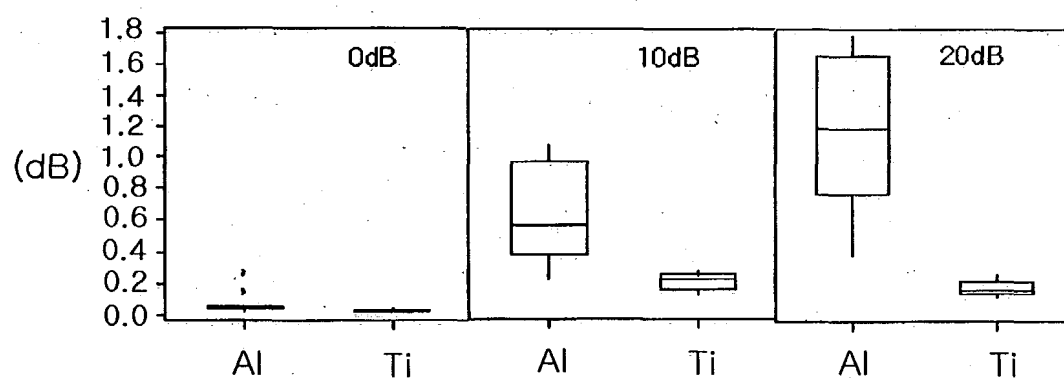


FIG. 7b